

In July 2012, A&D Co., Ltd. exhibited an FIB (focused ion beam) and EB (electron beam) at the Microscopy & Microanalysis Conference in Phoenix, Arizona. This exhibition is one of the biggest within the microscience field. We are sure of its affinity with our products. It was a precious opportunity to expose our company and products in the American market.

Our exhibition was mainly about FIBs, EB columns, and high voltage power supplies.

Pictures



Exhibitor information

A&D Company Limited	
Booth # 205 Map It	
3-23-14 Higashi Ikebukuro Toshima Ku, Tokyo 170-0013 Japan Phone: +81-3-5391-6132 Click here to send email URL: (http:// is required) http://www.aandd.jp/products/dsp/eb/	
Exhibitor Information	
Profile A&D Company Limited in Japan has been manufacturing FIB, SEM, and Beam Controller and Imaging Systems for more than 30 years. A&D FIB and SEM columns are available not only for R&D but also for SEM/FIB system manufacturing such as the 100kV EB Lithography System EBL-100I, FIB ion-implanter FIB-100nI, and ToF-SIMS systems. Keyword: FIB, EB, HV power supply	
Categories <ul style="list-style-type: none"> • E Beam Lithography • FIB accessories • Focused Ion Beam Systems/Workstations • Scanning Electron Microscopes • Scanning Tunneling Microscopes • Surface Analysis 	